

(19)



JAPANESE PATENT OFFICE

PATENT ABSTRACTS OF JAPAN

(11) Publication number: 2000065942 A

(43) Date of publication of application: 03.03.00

(51) Int. Cl. G01T 1/29  
G21K 5/04  
// H01J 37/317

(21) Application number: 10247825

(71) Applicant: NISSIN ELECTRIC CO LTD

(22) Date of filing: 17.08.98

(72) Inventor: NAITO KATSUO  
TANJO MASAYASU

(54) MEASURING APPARATUS FOR BEAM QUANTITY

COPYRIGHT: (C)2000,JPO

(57) Abstract:

PROBLEM TO BE SOLVED: To obtain a measuring apparatus by which the beam quantity of an ion beam can be measured precisely by a method wherein, even when secondary ions and secondary electrons are generated inside a Faraday cup, they are suppressed from escaping from the Faraday cup.

SOLUTION: A Faraday cup 20 has a structure in which it is divided electrically into a cylindrical sidewall part 21 and a bottom part 22 which catches an ion beam 2. A beam ammeter 12 is connected to the bottom part 22. In addition, a DC power supply 24 which applies a positive voltage to the sidewall part 21 is installed across the sidewall part 21 and the bottom part 22. In addition, the bottom part 22 is formed in a shape which is sharpened toward a side on which the ion beam 2 is incident.

